

# Tuning Microchannel Wettability and Fabrication of Multiple-step Laplace Valves

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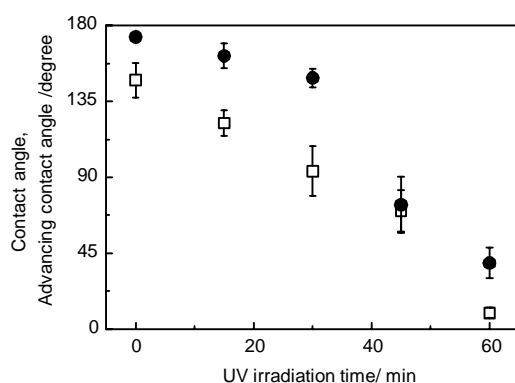
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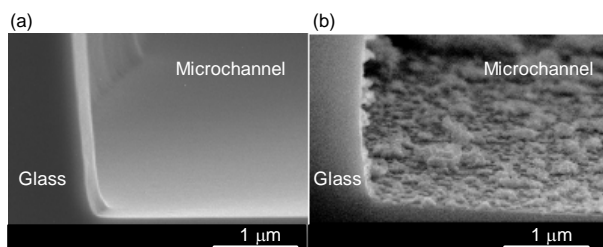
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**Fig. S1** Irradiation time dependencies of contact angle (open squares) and advancing contact angle (closed circles) of OTM plate surface.



**Fig. S2** SEM images of the microchannel cross sections before (a) and after (b) titania modification.